



IN THE U.S. PATENT AND TRADEMARK OFFICE

176

Applicant(s): Horacio D. ESPINOSA et al.

For: NANOTIPPED DEVICE AND METHOD

Serial No.: 10/801 928 Group: 3754

Confirmation No.: 2330

Filed: March 16, 2004 Examiner: Unknown

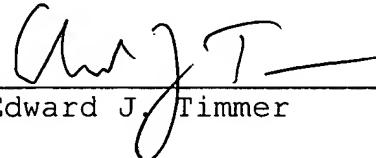
Atty. Docket No.: NU23014

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

FIRST CLASS MAILING CERTIFICATE

Sir:

I hereby certify that this correspondence is being deposited with the United States Postal Service under 37 CFR 1.8 as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on July 28, 2004.

  
Edward J. Timmer

EJT/ad

P.O. Box 770  
Richland, MI 49083

Tel: (269) 629-9136  
Fax: (269) 629-4962

Correspondence: Information Disclosure Statement including enclosures listed thereon



PATENT APPLICATION

July 27, 2004

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant(s): Horacio D. ESPINOSA et al.

For: NANOTIPPED DEVICE AND METHOD

Serial No.: 10/801 928 Group: 3754

Confirmation No.: 2330

Filed: March 16, 2004 Examiner: Unknown

Atty. Docket No.: NU23014

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

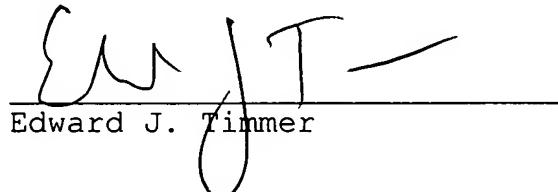
INFORMATION DISCLOSURE STATEMENT

Sir:

This Information Disclosure Statement is being filed in accordance with the duty of disclosure under 37 C.F.R. § 1.56 and pursuant to 37 C.F.R. § 1.97-1.98. Enclosed herewith is Form PTO-1449 including copies of the documents listed under the heading "Other Documents." Accordingly, further comment at this point in time should not be necessary.

Further consideration is respectfully solicited.

Respectfully submitted,

  
Edward J. Timmer

EJT/ad

P.O. Box 770  
Richland, MI 49083

Tel: (269) 629-9136  
Fax: (269) 629-4962

Encl: Form PTO-1449 (2 pages)  
First Class Mailing Certificate  
Postal Card

INFORMATION DISCLOSURE CITATION	Applicant : Horacio D. Espinosa et al. Serial No.: 10/801 928 Group : 3754	Page 1 of 2 Filed : March 16, 2004 Atty. Ref. : NU23014
---------------------------------------	--	---

JUL 30 2004

## U. S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date

## FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

## OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AA	de Boer, M. et al., "Micromachining of Buried Channels in Silicon," J. Microelectromech. 9(1), Mar 2000, p. 94-103.
AB	Hong, M. et al., "Scanning nanolithography using a material-filled nanopipette," Appl. Phys. Lett. 77(16), Oct 2000, p. 2604-2606.
AC	Hong, S. et al., "A Nanoplotter with Both Parallel and Serial Writing Capabilities," Science 288, June 2000, p. 1808-1811.
AD	Lewis, A. et al., "Fountain pen nanochemistry: Atomic force control of chrome etching," Appl. Phys. Lett. 75(17), Oct 1999, p. 2689-2691.
AE	Lieberman, K. et al., "Multifunctional, micropipette based force cantilevers for scanned probe microscopy," Appl. Phys. Lett. 65(5), Aug 1994, p. 648-650.
AF	Minne, S. et al., "Automated parallel high-speed atomic force microscopy," Appl. Phys. Lett. 72(18), May 1998, p. 2340-2342.
AG	Minne, S. et al., "Centimeter scale atomic force microscope imaging and lithography," Appl. Phys. Lett. 73(12), Sep 1998, p. 1742-1744.
AH	Papautsky, I. et al., "Micromachined Pipette Arrays," IEEE Trans. Biomed. Eng. 47(6), p. 812-819.

EXAMINER	DATE CONSIDERED
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE CITATION	Applicant : Horacio D. Espinosa et al. Serial No.: 10/801 928 Group : 3754	Page 2 of 2 Filed : March 16, 2004 Atty. Ref. : NU23014
---------------------------------------	--	---

## U. S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date

## FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

## OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AI	Piner, R. et al., "'Dip-Pen' Nanolithography," Science 283, Jan 1999, p. 661-663.
AJ	Rangelow, I. et al., "'NANOJET': Tool for the nanofabrication," J. Vac. Sci. Technol. B 19(6), Nov/Dec 2001, p. 2723-2726.
AK	Shalom, S. et al., "A micropipette force probe suitable for near-field scanning optical microscopy," Rev. Sci. Instrum. 63(9), Sep 1992, p. 4061-4065.
AL	Vettiger, P. et al., "The 'Millipede' - More than one thousand tips for future AFM data storage," IBM J. Res. Devlop. 44(3), May 2000, p. 323-340.
AM	Vettiger, P. et al., "The 'Millipede' - Nanotechnology Entering Data Storage," IEEE Trans. on Nanotech. 1(1), Mar 2002, p. 39-55.
AN	Zhang, M. et al., "A MEMS nanoplotter with high-density parallel dip-pen nanolithography probe arrays," Nanotechnology 13, 2002, p. 212-217.
AO	Zou, J. et al., "Conductivity-based contact sensing for probe arrays in dip-pen nanolithography," Appl. Phys. Lette. 83(3), Jul 2003, p. 581-583.

EXAMINER	DATE CONSIDERED
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.